

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	PATENT APPLICATION
Inventor: Apostolos Voutsas)	
Serial No.: Not Yet Assigned)	Attorney Docket No. SLA 0592
Filed: Herewith)	<i>Steven</i> <i>#2</i>
Title: METHOD FOR FORMING SILICON FILMS WITH TRACE IMPURITIES)	9-2601

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09/893866

06/28/01

Hon. Assistant Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97

Sir:

Listed on attached Form PTO-1449 is information submitted pursuant to 37 C.F.R. §1.56. A copy of each listed publication is submitted herewith.

Applicant respectfully requests that the listed information be considered by the Examiner and made of record in the above-identified application.

(Date)

Respectfully submitted,

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